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TABLE OF CONTENTS

MOS1

NOVEL HIGH ABSORPTION CERAMIC COATING MADE BY PLASMA-CHEMICAL OXIDATION	1
<i>U. Hausmann, M. Gabl, J. Schmidt</i>	
DESIGN AND MANUFACTURING OF OPTICAL ASSEMBLIES FOR HIGH-END ELECTRO-OPTICAL SYSTEMS: KEY ISSUES AND CHALLENGES	3
<i>S. Joseph, E. Kassis, A. Shienmann</i>	
OPTO-THERMO-MECHANICAL SIMULATION AND AUTOMATED ROBUST DESIGN OPTIMIZATION OF A LENS SYSTEM	5
<i>S. Kunath, D. Asoubar, H. Schuler</i>	
DESIGN OF REFOCUSING SYSTEM FOR A HIGH RESOLUTION SPACE TDICCD CAMERA WITH WIDE-FIELD OF VIEW	7
<i>S. Lv, J. Liu</i>	
EXPERIMENTAL STUDY ON SPECTRAL ATTENUATION AT LOW VISIBILITY ARTIFICIAL FOG IN VISIBLE AND NEAR INFRARED BAND	13
<i>A. Mayra, E. Hietala, M. Kutila</i>	
SPACEBORNE MULTIBAND UV ATMOSPHERIC DETECTOR WITH TWO FIELDS	15
<i>Q. Xue, X. Wang</i>	

MOS2

INFLUENCE OF DIFFERENT MATERIALS IN THE POLISHING MATERIAL REMOVAL OF STEEL SAMPLES	17
<i>R. Almeida, R. Borret, D. Harrison, A. Desilva</i>	
ALTERNATIVE TECHNOLOGIES FOR ASPHERE AND FREEFORM MANUFACTURING	19
<i>T. Arnold, G. Bohm, H. Paetzelt, F. Frost</i>	
FIGURE ERROR CORRECTION OF ALUMINIUM MIRRORS BY DETERMINISTIC REACTIVE ION-BEAM MACHINING	21
<i>J. Bauer, M. Ulitschka, F. Frost, T. Arnold</i>	
CHARACTERISTICS OF DIAMOND TURNED NIP SMOOTHED WITH IBP	23
<i>Y. Li, H. Takino, F. Frost</i>	
MANUFACTURING HIGH PRECISION OPTICAL FLATS TO $\lambda/75$ PV USING MRF AND SSI	25
<i>C. Maloney, C. Supranowitz, P. Dumas, J. Lormeau</i>	

MOS3

OPTIMIZING DUCTILE MODE GRINDING IN TERMS OF GENERATED LEVEL OF SURFACE ROUGHNESS: $RQ = F(HCUT)$	28
<i>O. Fahnle, M. Doetz</i>	
FREEFORM MONOLITHIC MULTI-SURFACE TELESCOPE MANUFACTURING	31
<i>J. Lawson, T. Blalock, K. Medicus</i>	
LIQUID PHASE IMPRINTING ON GALLIUM/PDMS BOUNDARY FOR ON-DEMAND LENS FABRICATION	33
<i>K. Nakakubo, H. Nomada, H. Yoshioka, K. Morita, Y. Oki</i>	
DIRECT LASER FABRICATION OF MICRO FRESNEL LENSES	35
<i>M. Pfeifer, S. Buettner, R. Zhang, M. Serbay, S. Weissmantel</i>	
FABRICATION OF LENS ARRAY WITH DLP BASED 3D PRINTING AND THERMAL FINISHING	37
<i>M. Riahi, Y. Honarmand, M. Rahimzadeh, Z. Barhikhteh</i>	

MOS4

POLISHING SHAPE CORRECTION OF FLAT HARDENED STEEL SAMPLES	39
<i>R. Almeida, R. Borret, M. Pohl, D. Harrison, A. Desiva</i>	
INFLUENCE OF DIFFERENT COOLANTS ON DUCTILE MODE PROCESSING THROUGH ULTRA-SONIC ASSISTED DIAMOND TURNING OF TUNGSTEN CARBIDE	41
<i>M. Doetz, O. Dambon, F. Klocke, O. Fahnle</i>	
TOLERANCING ASPHERES BASED ON LARGE BATCH SIZE MANUFACTURING	43
<i>S. Kiontke, S. Wickenhagen, U. Fuchs</i>	
MANUFACTURING HIGH PRECISION MILD CYLINDERS USING CLASSICAL STRESSED MIRROR POLISHING, MRF AND SSI TECHNOLOGIES	45
<i>B. Szterner, C. Maloney, P. Dumas, J. Lormeau, S. Gogler</i>	

MOS5

THE DEVELOPMENT OF EXTREME ULTRAVIOLET / SOFT X-RAY OPTICAL SYSTEM AT SKLAO	48
<i>C.-S. Jin, L.-P. Wang, Y. Xie, B. Yu, H. Wang, J. Yu, H.-T. Zhang, Y. Liu, F. Zhou, B.-Y. Guo, W. Huang</i>	
MANUFACTURING AND INDUSTRIALIZATION OF EUV LITHOGRAPHY OPTICS	50
<i>M. Lowisch, T. Heil</i>	
DEVELOPMENT OF IRIIDIUM COATED SILICON X-RAY MIRRORS FOR LOBSTER EYE ASTRONOMICAL TELESCOPES	51
<i>V. Stehlikova, A.-C. Probst, O. Nentvich, M. Urban, A. Inneman, L. Siegler, V. Marsikova, T. Dohring</i>	
CHARACTERIZATION OF EUV OPTICAL COMPONENTS	53
<i>M. Trost, M. Hauptvogel, S. Schroder, R. Jende, R. Steinkopf, S. Risse, M. Perske, H. Pauer, T. Fiedler, T. Feigl</i>	
TWO-COLOR PRIME LASER OF SUBNANOSECOND PULSES FOR EUV LITHOGRAPHY	55
<i>A. Zhevlakov, V. Bespalov, R. Seisyan</i>	

MOS6

OPTIMIZATION OF STRUCTURE AND MANUFACTURING CAPABILITIES OF LIGHT- WEIGHTED MIRRORS PRODUCTION	57
<i>M. Abdulkadyrov, N. Vladimirov, N. Dobrikov, A. Ignatov, V. Patrikeev, A. Semenov</i>	
RAPID FABRICATION STRATEGY FOR 1.5M OAP USING CCOS METHOD	59
<i>N/A</i>	
THE MESSIER PATH FINDER: A HIGH PERFORMANCE, WIDE FIELD, FAST AND DISTORTION FREE TELESCOPE USING A CURVED DETECTOR	60
<i>E. Muslimov, E. Hugot, X. Wang, D. Gabaud, P. Vola, G. Lemaitre</i>	
MANUFACTURING LARGE APERTURE AND HIGH DIAMETER-TO-THICKNESS RATIO FLAT MIRROR AS THE PROTOTYPE OF TMT M3	62
<i>N/A</i>	

MOS7

FLUID JET POLISHING OF STRUCTURES SURFACES	63
<i>R. Almeida, R. Borret, J. Raab, M. Schneckenburger, M. Speich, D. Wiedmann</i>	
ABLATION OF FUSED SILICA WITH HIGH POWER Q-SWITCH CO₂-LASER RADIATION	65
<i>K. Braun, C. Weingarten, E. Willenborg, A. Temmler</i>	
ZIGZAG GRATING WITH QUASI-RANDOM ARRAY FOR SINGLE ORDER DIFFRACTION	67
<i>Z. Liu, T. Pu, L. Shi, C. Xie</i>	
E²-PCGS: EFFICIENCY ENHANCED PULSE COMPRESSION GRATINGS FOR INDUSTRIAL APPLICATIONS	69
<i>R. Muller, M. Bender, E. Piechocka, U. Suß, M. Klaus, M. Oliva</i>	
HIGH-ORDER SUPPRESSION OF QUASI-TRIANGLE ARRAY TRANSMISSION GRATINGS	71
<i>T. Pu, Z. Liu, L. Shi, C. Xie</i>	

MOS8

REFRACTIVE INDEX MODULATION IN MEDIA WITH SATURABLE PHOTOLENSITIVITY	74
<i>S. Mokhov</i>	
COMPUTER-CONTROLLED PROCESS OF OFF-AXIS ASPHERICS PRODUCTION WITH APHERICITY UP TO 20MM	76
<i>A. Semenov, M. Abdulkadyrov, S. Belousov, A. Ignatov, V. Patrikeev</i>	
3D DIRECT LASER WRITING OF MICRO CORNER CUBE RETROREFLECTORS	78
<i>Y. Tanguy, F. Niesler, M. Thiel</i>	
BEAM SHAPERS FOR FRACTIONAL TOPOLOGICAL CHARGES	80
<i>R. Tudor, C. Kusko, M. Kusko, M. Mihailescu, A. Avram</i>	
ASPHERICAL HIGH-SPEED VARIFOCAL MIRROR FOR CATADIOPTRIC MINIATURE TELEPHOTO OPTICS	82
<i>M. Wapler, F. Lemke, G. Alia, U. Wallrabe</i>	

MOS9-JOINT SESSION WITH SPIE

WIDE-RANGING ROUGHNESS ANALYSIS OF OPTICAL SURFACES	84
<i>N. Felde, L. Coriand, S. Schroder, A. Tunnermann</i>	

MOS10-JOINT SESSION WITH SPIE

METROLOGY FOR FREEFORM AND WAFER LEVEL OPTICS BY UA3P	86
<i>T. Morishita, K. Kubo, D. Ramm</i>	
IN SITU LASER POLISHING OPTIMIZATION METHOD: CONTROL OF LASER SURFACE OPTIMIZATION (C-LASSO)	88
<i>R. Rascher, C. Vogt, O. Faehnle</i>	
WAVEFRONT EVALUATION METHOD BASED ON IMAGING PERFORMANCE: RELATIVE WAVEFRONT GRADIENT DEVIATION	91
<i>B. Xuan, J.-J. Xie</i>	
Author Index	